

DECLARATION (37 CFR 1.63) FOR UTILITY OR DESIGN APPLICATION USING AN APPLICATION DATA SHEET (37 CFR 1.76)

Title of Invention	A METHOD AND RESULTING STRUCTURE FOR FABRICATING DRAM CELL STRUCTURE USING OXIDE LINE SPACER
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As the below named inventor(s), I/we declare that:

This declaration is directed to:

The attached application, or
 Application No. , filed on ,
 as amended on _____ (if applicable);

I/we believe that I/we am/are the original and first inventor(s) of the subject matter which is claimed and for which a patent is sought;

I/we have reviewed and understand the contents of the above-identified application, including the claims, as amended by any amendment specifically referred to above;

I/we acknowledge the duty to disclose to the United States Patent and Trademark Office all information known to me/us to be material to patentability as defined in 37 CFR 1.56, including for continuation-in-part applications, material information which became available between the filing date of the prior application and the national or PCT International filing date of the continuation-in-part application.

All statements made herein of my/our own knowledge are true, all statements made herein on information and belief are believed to be true, and further that these statements were made with the knowledge that willful false statements and the like are punishable by fine or imprisonment, or both, under 18 U.S.C. 1001, and may jeopardize the validity of the application or any patent issuing thereon.

FULL NAME OF INVENTOR(S)

Inventor 1 Mieno Fumitake Date: 2003, 12, 16

Signature: F. Mieno Citizen of: Japan

Inventor 2 Bong Jae Lee Date: Nov. 25, 2003

Signature: B. J. Lee Citizen of: Korea

Inventor 3 Guoqing Chen Date: Nov. 25, 2003

Signature: G. Chen Citizen of: Peoples Republic of China

Additional inventors are being named on additional form(s) attached hereto.

**POWER OF ATTORNEY
and
CORRESPONDENCE ADDRESS
INDICATION FORM**

Application Number	
Filing Date	
First Named Inventor	Mieno Fumitake et al.
Title	A METHOD AND RESULTING STRUCTURE FOR FABRICATING DRAM CELL STRUCTURE USING OXIDE LINE SPACER
Art Unit	
Examiner Name	
Attorney Docket Number	021653-004600US

I hereby appoint:

Practitioners associated with the Customer Number

20350

OR

Practitioner(s) named below:

Name	Registration Number

as my/our attorney(s) or agent(s) to prosecute the application identified above, and to transact all business in the United States Patent and Trademark Office connected therewith.

Please recognize or change the correspondence address for the above-identified application to:

The address associated with the above-mentioned Customer Number:

OR

The address associated with Customer Number:

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OR

Firm or
Individual Name

Address

Address

City

State

ZIP

Country

Telephone

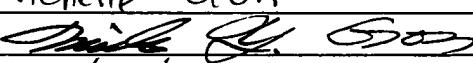
Fax

I am the:

Applicant/Inventor.

Assignee of record of the entire interest. See 37 CFR 3.71.
Statement under 37 CFR 3.73(b) is enclosed. (Form PTO/SB/96).

SIGNATURE of Applicant or Assignee of Record

Name	Michelle Gton		
Signature			
Date	11/26/03	Telephone	86-21-50802000

NOTE: Signatures of all the inventors or assignees of record of the entire interest or their representative(s) are required. Submit multiple forms if more than one signature is required, see below*.

*Total of _____ forms are submitted.

Attorney Docket No. 021653-003400US

STATEMENT UNDER 37 CFR 3.73(b)

Applicant/Patent Owner: _____

Application No./Patent No.: / Filed/Issue Date: /

Entitled: A METHOD AND RESULTING STRUCTURE FOR FABRICATING DRAM CELL STRUCTURE USING OXIDE LINE SPACERSemiconductor Manufacturing International (Shanghai) Corporation, a corporation organized under the laws of the PRC

(Name of Assignee)

(Type of Assignee, e.g., corporation, partnership, university, etc.)

states that it is:

1. the assignee of the entire right, title, and interest; or
2. an assignee of less than the entire right, title and interest.

The extent (by, percentage) of its ownership interest is ____ %

in the patent application/patent identified above by virtue of either:

A. An assignment from the inventor(s) of the patent application/patent identified above. The assignment was recorded in the United States Patent and Trademark Office at Reel ____, Frame ____, or for which a copy thereof is attached.

OR

B. A chain of title from the inventor(s), of the patent application/patent identified above, to the current assignee as shown below:

1. From: _____ To: _____
 The document was recorded in the United States Patent and Trademark Office at
 Reel ____, Frame ____, or for which a copy thereof is attached.

2. From: _____ To: _____
 The document was recorded in the United States Patent and Trademark Office at
 Reel ____, Frame ____, or for which a copy thereof is attached.

Additional documents in the chain of title are listed on a supplemental sheet.

Copies of assignments or other documents in the chain of title are attached.

[NOTE: A separate copy (i.e., the original assignment document or a true copy of the original document) must be submitted to Assignment Division in accordance with 37 CFR Part 3, if the assignment is to be recorded in the records of the USPTO. See MPEP 302.8]

The undersigned (whose title is supplied below) is authorized to act on behalf of the assignee.

11/26/03

Date

86-21-5080-2000

Telephone number

Michelle Gion

Typed or printed name

Michelle Gion

Signature

Chief Legal Officer

Title

60077949 v1

ASSIGNMENT OF PATENT APPLICATION

JOINT

WHEREAS, Mieno Fumitake of 18 Zhang Jiang Road, Pudong New Area, Shanghai, 201203 People's Republic of China; Bong Jae Lee of 18 Zhang Jiang Road, Pudong New Area, Shanghai, 201203 People's Republic of China; Guoqing Chen of 18 Zhang Jiang Road, Pudong New Area, Shanghai, 201203 People's Republic of China, hereinafter referred to as "Assignors," are the inventors of the invention described and set forth in the below-identified application for United States Letters Patent:

Title of Invention: **A METHOD AND RESULTING STRUCTURE FOR FABRICATING DRAM CELL STRUCTURE USING OXIDE LINE SPACER**

Date(s) of execution of Declaration:

Filing Date:

Application No.:

WHEREAS, Semiconductor Manufacturing International (Shanghai) Corporation, a corporation organized under the laws of the People's Republic of China, located at 18 Zhang Jiang Rd., Pudong New Area, Shanghai, 201203, People's Republic of China, hereinafter referred to as "ASSIGNEE," is desirous of acquiring an interest in the invention and application and in any U.S. Letters Patent and Registrations which may be granted on the same;

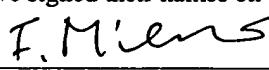
For good and valuable consideration, receipt of which is hereby acknowledged by Assignors, Assignors have assigned, and by these presents do assign to Assignee all right, title and interest in and to the invention and application and to all foreign counterparts (including patent, utility model and industrial designs), and in and to any Letters Patent and Registrations which may hereafter be granted on the same in the United States and all countries throughout the world, and to claim the priority from the application as provided by the Paris Convention. The right, title and interest is to be held and enjoyed by Assignee and Assignee's successors and assigns as fully and exclusively as it would have been held and enjoyed by Assignors had this Assignment not been made, for the full term of any Letters Patent and Registrations which may be granted thereon, or of any division, renewal, continuation in whole or in part, substitution, conversion, reissue, prolongation or extension thereof.

Assignors further agree that they will, without charge to Assignee, but at Assignee's expense, (a) cooperate with Assignee in the prosecution of U.S. Patent applications and foreign counterparts on the invention and any improvements, (b) execute, verify, acknowledge and deliver all such further papers, including patent applications and instruments of transfer, and (c) perform such other acts as Assignee lawfully may request to obtain or maintain Letters Patent and Registrations for the invention and improvements in any and all countries, and to vest title thereto in Assignee, or Assignee's successors and assigns.

Assignors hereby authorize and request Townsend and Townsend and Crew LLP, Two Embarcadero Center, Eighth Floor, San Francisco, CA 94111-3834, to insert herein above the application number and filing date of said application when known.

IN TESTIMONY WHEREOF, Assignors have signed their names on the dates indicated.

Dated: 2003. 12. 16.


Mieno Fumitake

Assignment

Attorney Docket No.: 021653-004600US

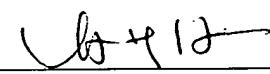
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Dated: Nov. 25, 2003



Bong Jae Lee

Dated: Nov. 25, 2003



Guoqing Chen

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